Application No. 10/814,252

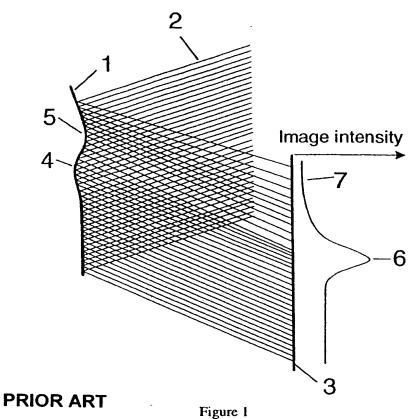
Applicant: István Endre LUKÁCS et al.

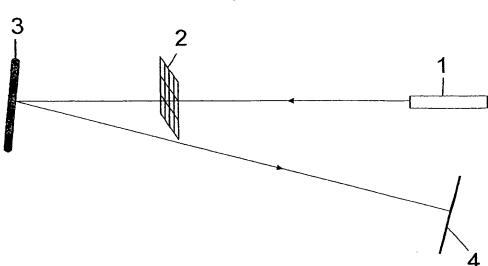
Title: APPARATUS AND MEASUREMENT PROCEDURE FOR THE FAST, QUANTITATIVE, NON-CONTACT TOPOGRAPHIC INVESTIGATION OF SEMI-CONDUCTOR WAFERS AND OTHER MIRROR LIKE SURFACE Responsive to Official Communication dated: February 3, 2005

REPLACEMENT SHEET

1/2







PRIOR ART

Figure 2

Confirmation No. 6976 Attorney Docket No. P25051

Application No. 10/814,252

Applicant: István Endre LUKÁCS et al.

Title: APPARATUS AND MEASUREMENT PROCEDURE FOR THE FAST, QUANTITATIVE, NON-CONTACT TOPOGRAPHIC INVESTIGATION OF SEMI-CONDUCTOR WAFERS AND OTHER MIRROR LIKE SURFACE Responsive to Official Communication dated: February 3, 2005

REPLACEMENT SHEET

2/2



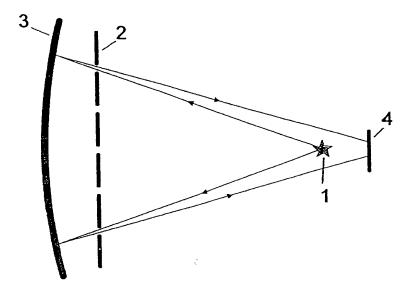


Figure 3

PRIOR ART

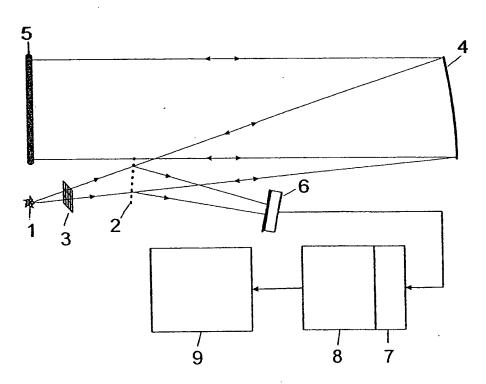


Figure 4